		_	CAP.	<u> </u>										
FO	RM P	то - 1	THAUCT			ATTORN	EY DOC	KET NO.:	ASC-066	5				
INF	ORM	1ATIC	N DISCLOSUI	RE STATEM	IENT	APPLICA	.NT(S): V	Westhoff e	al.					
						SERIAL N	NO.: 10/7	65,372			- 602			
						FILING DATE: January 27, 2004 GROUP: 2812								
				U.S.	PATENT	T DOCUMENTS								
EXA INIT			DOCUMENT NUMBER	DATE	NAME	ME CLASS SUB FILING CLASS APPRO								
d	PM	Al	4,914,488	04/03/1990	Yamane e	Yamane et al								
		A2	4,960,728	10/02/1990	Schaake e	ke et al								
		A3	6,208,005	03/27/2001	Mitra									
		A4	6,515,335	02/04/2003	Christians	en et al			7					
1	<u>/</u>	A5	2002/0185686	12/12/2002	Christians	en et al		1						
				FOREI	GN PATE	NT DOCU	MENTS							
EXA INIT			DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	FILING DATE	ABSTRA ONLY	СТ	ENGLISH LANG (Y/N)			
				-										
						1								
											-			
				OTHER AR	T, JOURN	IAL ARTI	CLES, E	ETC.						
EXA INIT		ОТН	ER DOCUMENT	S: (Including	Author, Tit	le, Date, Re	levant Pag	es, Place of	f Publicati	on) ,				
do	M	Cl	International Se	arch Report for	Internationa	d Application	n No. PCT	/US2004/00	2282 10/1	5/04				
							· · · · · · · · · · · · · · · · · · ·							
					··· · · ·	· ·								
								-						
			2.			<u> </u>								
EXA	MINE	er C	Y EMels	evr		DATE CO	NSIDERI	ED (0/191	05	-			

DEC 2 0 2000 RM PTO - 1449 ATTORNEY DOCKET NO.: ASC-066 INFORMATION DISCLOSURE STATEMENT APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 FILING DATE: January 27, 2004 GROUP: 2812 U.S. PATENT DOCUMENTS **CLASS** SUB DOCUMENT DATE NAME FILING DATE IF EXAM. **CLASS** APPROPRIATE INIT. NUMBER 06/14/2001 Sugawara et al. / **A6** 2001/0003364 Alm **A7** 2001/0014570 08/16/2001 Wenski et al. Yamazaki et al. 2002/0043660 04/18/2002 **A8** Fitzgerald 07/04/2002 2002/0084000 **A9** 07/25/2002 Chu et al. A10 2002/0096717 2002/0100942 08/01/2002 Fitzgerald et al. -A11 09/05/2002 Fitzgerald 2002/0123167 A12 2002/0123183 09/05/2002 Fitzgerald -A13 2002/0125471 09/12/2002 Fitzgerald et al. A14 A15 2002/0168864 11/14/2002 Cheng et al. 12/12/2002 Christiansen et al. 2002/0185686 **A16** 01/02/2003 Doyle et al. A17 2003/0003679 Som 01/16/2003 Hammond et al. A18 2003/0013323 Fitzgerald et al. 2003/0034529 02/20/2003 A19 A20 03/06/2003 Wenski et al. 2003/0041798 Fitzgerald / A21 2003/0057439 03/27/2003 06/05/2003 Braithwaite et al. A22 2003/0102498 10/23/2003 Chu et al. 2003/0199126 A23 2003/0203600 10/30/2003 Chu et al. A24 A25 2003/0215990 11/20/2003 Fitzgerald et al. / 11/27/2003 Christiansen / A26 2003/0218189 2003/0227057 12/01/2003 Lochtefeld et al. A27 2004/0005740 01/01/2004 Lochtefeld et al. A28 01/22/2004 Bhattacharyya / A29 2004/0014304 06/06/2003 A30 2004/0031979 02/19/2004 Lochtefeld -03/04/2004 09/02/2003 2004/0041210 Mouli ___ A31 & HMelsen 10/19/2005 DATE CONSIDERED

*- Already listed on 105 (1449) filed on Nov. 5,2004

EXAMINER

INFORMATION DISCLOSURE STATEMENT

ATTORNEY DOCKET NO.: ASC-066

APPLICANT(S): Westhoff et al.

SERIAL NO.: 10/765,372

FILING DATE: January 27, 2004 GROUP: 2812

1	T T	C	DA	TENT	DOCI	IMENTS
- 1			PA		1 11 11 11	IIVITIVI 3

EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME .	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
yon	A32	2004/0075149	04/22/2004	Fitzgerald et al.			07/23/2003			
1	A33	4,010,045	03/01/1977	Ruehrwein /						
	A34	4,710,788	12/01/1987	Dambkes et al.						
1	A35	4,900,372	02/13/1990	Lee et al.						
	A36	4,987,462	01/22/1991	Kim et al.		7				
	A37	4,990,979	02/05/1991	Otto 🗸		1				
	A38	4,997,776	03/05/1991	Harame et al.		1				
	A39	5,013,681	05/07/1991	Godbey et al.						
	A40	5,091,767	02/25/1992	Bean et al. /						
	A41	5,097,630	03/24/1992	Maeda et al. /		•				
	A42	5,155,571	10/13/1992	Wang et al.						
	A43	5,159,413	10/27/1992	Calviello et al.						
	A44	5,166,084	11/24/1992	Pfiester /						
	A45	5,177,583	01/05/1993	Endo et al.		· · · · · · · · · · · · · · · · · · ·				
	A46	5,202,284	04/13/1993	Kamins et al. /						
	A47	5,207,864	05/04/1993	Bhat et al.						
	A48	5,208,182	05/04/1993	Narayan et al.						
	A49	5,210,052	05/11/1993	Takasaki /						
	A50	5,212,110	05/18/1993	Pfiester et al.						
	A51	5,221,413	06/22/1993	Brasen et al. /						
	A52	5,240,876	08/31/1993	Gaul et al.			·			
	A53	5,241,197	08/31/1993	Murakami et al.						
	A54	5,250,445	10/05/1993	Bean et al. /						
	A55	5,252,173	10/12/1993	Inoue		-				
	A56	5,279,687	01/18/1994	Tuppen et al.						
	A57	5,285,086	02/08/1994	Fitzgerald -						
V	A58	5,291,439	03/01/1994	Kauffmann et al						
XAMINI	ER (Mala_		DATE CONSIDERED /0/19/05						

INFORMATION DISCLOSURE STATEMENT

ATTORNEY DOCKET NO.: ASC-066

APPLICANT(S): Westhoff et al.

SERIAL NO.: 10/765,372

2823

			U.S. PAT	ENT DOCUMENT	rs .			
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
dum.	A59	5,298,452	03/29/1994	Meyerson /	_			
1	A60	5,308,444	05/03/1994	Fitz et al.				
	A61	5,310,451	05/10/1994	Tejwani et al.		/		
	A62	5,316,958	05/31/1994	Meyerson /		/		
	A63	5,346,848	09/13/1994	Grupen- Shemansky et al.		/		
	A64	5,374,564	12/20/1994	Bruel	1		·	
	A65	5,399,522	03/21/1995	Ohori	 		<u> </u>	
$\overline{}$	A66	5,413,679	05/09/1995	Godbey /	 			
	A67	5,424,243	06/13/1995	Takasaki -	 			
	A68	5,425,846	06/20/1995	Koze et al. /				
1	A69	5,426,069	06/20/1995	Selvakumar et al.	1 1			
	A70	5,426,316	06/20/1995	Mohammad /				
	A71	5,442,205	08/15/1995	Brasen et al.				
	A72	5,461,243	10/24/1995	Ek et al.				
	A73	5,461,250	10/24/1995	Burghartz et al.				
	A74	5,462,883	10/31/1995	Dennard et al.				
	A75	5,476,813	12/19/1995	Naruse				
	A76	5,479,033	12/26/1995	Baca et al. /				
	A77	5,484,664	01/16/1996	Kitahara et al.			·	
	A78	5,523,243	06/04/1996	Mohammad _				
	A79	5,523,592	06/04/1996	Nakagawa et al. /				
	A80	5,534,713	07/09/1996	Ismail et al.				
	A81	5,536,361	07/16/1996	Kondo et al				
	A82	5,540,785	07/30/1996	Dennard et al. >				
	A83	5,572,043	11/05/1996	Shimizu et al.				
	A84	5,596,527	01/21/1997	Tomioka et al.				
1	A85	5,617,351	04/01/1997	Bertin et al.				
EXAMIN	ER /	YMelson		DATE CONSIDERED 10/19/05				

INFORMATION DISCLOSURE STATEMENT

ATTORNEY DOCKET NO.: ASC-066

APPLICANT(S): Westhoff et al.

SERIAL NO.: 10/765,372

2823

				FILING DATE: January 27, 2004 GROUP: 2812						
			U.S. PAT	NT DOCUMENT	S					
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
Xum	A86	5,630,905	05/20/1997	Lynch et al.	-	7				
1	A87	5,633,516	05/27/1997	Mishima /		/	·			
	A88	5,659,187	08/01/1997	Legoues et al. =		1				
	A89	5,683,934	11/04/1997	Candelaria 🗸	· · · · ·	1				
	A90	5,698,869	12/16/1997	Yoshimi et al.		1				
	A91	5,714,777	02/03/1998	Ismail et al.		1				
	A92	5,728,623	03/17/1998	Mori _		7				
	A93 5,739,567 04/14/1998		Wong /							
	A94 5,759,898 06/02/1998		Ek et al.		-					
	A95 5,777,347 07/07/1998		Bartelink /							
	A96	5,786,612	07/28/1998	Otani et al.						
	A97	5,786,614	07/28/1998	Chuang et al.						
	A98	5,792,679	08/11/1998	Nakato /						
	A99	5,801,085	09/01/1998	Kim et al.						
	A100	5,808,344	09/15/1998	Ismail et al.						
	A101	5,810,924	09/22/1998	Legoues et al. /						
	A102	5,828,114	10/27/1998	Kim et al.						
	A103	5,847,419	12/08/1998	Imai et al		-				
	A104	5,859,864	01/12/1999	Jewell -						
-1	A105	5,877,070	03/02/1999	Goesele et al.						
	A106	5,891,769	04/06/1999	Liaw et al.						
	A107	5,906,708 .	05/25/1999	Robinson et al. /		· · · · · · · · · · · · · · · · · · ·				
	A108	5,906,951	05/25/1999	Chu et al.						
	A109	5,912,479	06/15/1999	Mori et al.			·			
7	A110	5,943,560	08/24/1999	Chang et al. /						
$\neg \vdash$	Alli	5,963,817	10/05/1999	Chu et al. /						
7.	A112	5,966,622	10/12/1999	Levine et al.						
V	A113	5,998,807	12/07/1999	Lustig et al. ~						
EXAMIN	ER /	X BMalsa		DATE CONSIDERED 10/19/05						

INFORMATION DISCLOSURE STATEMENT

ATTORNEY DOCKET NO.: ASC-066

APPLICANT(S): Westhoff et al.

SERIAL NO.: 10/765,372

	,		U.S. 1 A 1	ENT DOCUMENT	1.5		., —————
EXAM. INIT.	·	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
SIM	A114	6,010,937	01/04/2000	Karam et al.		7	
1	A115	6,013,134	01/11/2000	Chu et al.		7	
	A116	6,030,884	02/29/2000	Mori /		1	·
	A117	6,033,974	03/07/2000	Henley et al.		1	
	A118	6,033,995	03/07/2000	Muller -		1	
	A119	6,039,803	03/21/2000	Fitzgerald et al.		17	
	A120	6,058,044	05/02/2000	Sugiura et al. /			
	A121	6,059,895	05/09/2000	Chu et al.		V	
	A122 6,074,919 06/13/2000 Gar		Gardner et al.				
	A123	6,096,590	08/01/2000	Chan et al.			
	A124	6,103,559	08/15/2000	Gardner et al.	1		
	A125	6,107,653	08/22/2000	Fitzgerald /			
	A126	6,111,267	08/29/2000	Fischer et al			
	A127	6,117,750	09/12/2000	Bensahel et al			
	A128	6,124,617	09/26/2000	Ryum et al.			
	A129	6,130,453	10/10/2000	Mei et al.			
	A130	6,133,799	10/17/2000	Favors et al.			
	A131	6,140,687	10/31/2000	Shimomura et al.			
	A132	6,143,636	11/07/2000	Forbes et al			
	A133	6,153,495	11/28/2000	Kub et al.			
	A134	6,154,475	11/28/2000	Soref et al.			
	A135	6,160,303	12/12/2000	Fattaruso -			•
	A136	6,162,688	12/19/2000	Gardner et al.			
	A137	6,184,111	02/06/2001	Henley et al.			
	A138	6,191,006	02/20/2001	Mori -			
	A139	6,191,007	02/20/2001	Matsui et al			
	A140			Sugiyama et al.			
V	A141	6,194,722	02/27/2001	Fiorini et al			

INFORMATION DISCLOSURE STATEMENT

ATTORNEY DOCKET NO.: ASC-066

APPLICANT(S): Westhoff et al.

SERIAL NO.: 10/765,372

_				FILING DATE: January 27, 2004 GROUP: 2812						
			U.S. PAT	ENT DOCUMENT	S		-			
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
Altru	A142	6,204,529	03/20/2001	Lung et al.		7				
1	A143	6,207,977	03/27/2001	Augusto						
	A144	6,210,988	04/03/2001	Howe et al.		./				
	A145	6,218,677	04/17/2001	Broekaert	•					
	A146	6,232,138	05/15/2001	Fitzgerald et al						
	A147	6,235,567	05/22/2001	Huang						
	A148	6,242,324	06/05/2001	Kub et al.						
	A149	6,249,022	06/19/2001	Lin et al						
	A150	6,251,755	06/26/2001	Furukawa et al		1				
	A151	6,261,929	07/17/2001	Gehrke et al.						
	A152	6,266,278	07/24/2001	Harari et al.						
	A153	6,271,551	08/07/2001	Schmitz et al.						
	A154	6,271,726	08/07/2001	Fransis et al.			,			
	A155	6,291,321	09/18/2001	Fitzgerald /						
	A156	6,313,016	11/06/2001	Kibbel et al.	1					
	A157	6,316,301	11/13/2001	Kant /						
	A158	6,323,108	11/27/2001	Kub et al. /						
	A159	6,329,063	12/11/2001	Lo et al.						
	A160	6,335,546	01/01/2002	Tsuda et al.						
	A161	6,339,232	01/15/2002	Takagi /						
	A162	6,350,993	02/26/2002	Chu et al.						
	A163	6,352,909	03/05/2002	Usenko /						
	A164	6,368,733	04/09/2002	Nishinaga /						
	A165	6,372,356	04/16/2002	Thornton et al.		_				
	A166	6,399,970	06/04/2002	Kubo et al.						
	A167	6,403,975	06/11/2002	Brunner et al.						
	A168	6,406,589	06/18/2002	Yanagisawa -						
V	A169	6,407,406	06/18/2002	Tezuka /						
EXAMIN	ER C	Youlelson		DATE CONSIDERED 10/19/05						

INFORMATION DISCLOSURE STATEMENT

ATTORNEY DOCKET NO.: ASC-066

APPLICANT(S): Westhoff et al.

SERIAL NO.: 10/765,372

			U.S. PAT	ENT DOCUMENT	S		
EXAM.	1	DOCUMENT	DATE	NAME	CLASS	SUB	FILING DATE IF
NIT.		NUMBER				CLASS	APPROPRIATE
Alm	A170	6,420,937	07/16/2002	Akatsuka et al.	-	7	
1	A171	6,425,951	07/30/2002	Chu et al.			
	A172	6,429,061	08/06/2002	Rim			·
	A173	6,482,749	11/19/2002	Billington et al.		1	
	A174	6,518,644	02/11/2003	Fitzgerald			
	A175	6,521,041	02/18/2003	Wu et al.			
	A176	6,524,935	02/25/2003	Canaperi et al.			
	A177	6,525,338	02/25/2003	Mizushima et al.			
	A178	6,555,839	04/29/2003	Fitzgerald			
	A179	6,573,126	06/03/2003	Cheng et al.			
	A180	6,576,532	06/10/2003	Jones et al.			
	A181	6,583,015	06/24/2003	Fitzgerald et al.			
	A182	6,593,191	07/15/2003	Fitzgerald /			
	A183	6,594,293	07/15/2003	Bulsara et al.			
	A184	6,602,613	08/05/2003	Fitzgerald -			
	A185	6,603,156	08/05/2003	Rim /			
	A186	6,646,322	11/11/2003	Fitzgerald /			·
	A187	6,649,480	11/18/2003	Fitzgerald et al.			
	A188	6,677,192	01/13/2004	Fitzgerald /			
	A189	6,703,144	03/09/2004	Fitzgerald /			03/18/2003
	A190	6,703,688	03/09/2004	Fitzgerald /			07/16/2001
·	A191	6,709,903	03/23/2004	Christiansen /			04/30/2003
	A192	6,713,326	03/30/2004	Cheng et al.		-	03/04/2003
	A193	6,723,661	04/20/2004	Fitzgerald /			07/16/2001
	A194	6,724,008	04/20/2004	Fitzgerald /			07/16/2001
	A195	6,730,551	05/04/2004	Lee et al.			08/02/2002
	A196	6,737,670	05/18/2004	Cheng et al.			03/07/2003
V	A197	6,750,130	06/15/2004	Fitzgerald			01/07/2001

FORM	PTO	- 14	149 .				A	ATTORNEY DOCKET NO.: ASC-066							
INFOR	RMAT	OI	N DISCLOS	SURE S'	TATI	EMENT	А	PPLICANT	(S): West	hoff <i>et al</i> .					
							S	ERIAL NO.	: 10/765.3	172					
							1		•		2823				
							FILING DATE: January 27, 2004 GROUP: 2812								
					U	.S. PATE	NT DC	CUMENT	rs						
EXAM.			DOCUMEN	T	DAT	'E	NAME		CLASS	SUB	FILING DATE IF				
INIT.			NUMBER							CLASS	APPROPRIATE				
									ļ·						
	1_				_										
				· ·	FOR	EIGN PA	TENT	DOCUME	NTS						
EXAM INIT.		1	OCUMENT UMBER	DATE		COUN- TRY	CLASS	SUB CLASS	FILING DATE	ABSTRAC ONLY	T ENGLISH LANG (Y/N)				
11/11.		"	DIVIDER			CODE		CLASS	DATE	ONLI					
Alpm	BI	41	01 167	07/23/1	992	DE 🗸				N	Y (Abstract only)				
	B2	0 :	514 018	11/19/1	992	EP /				N	Y				
	В3	0:	587 520	03/16/1	994	EP ~			17	N	Y				
	B4 0 683 522				995	EP /			/	N	Y				
	B5	0.8	828 296	03/11/1	998	EP /				N	Υ .				
	В6	0.8	829 908	03/18/1	1998 EP /					N	Y				
	B7	0.8	338 858	04/29/1	1998 EP					N	Y (Abstract only)				
	B8	10	020 900	07/19/2	2000	EP /				N	Y				
	B9	1 1	174 928	01/23/2	002	EP /				N	Y				
	B10	23	342 777	04/19/2	000	GB /		/		Υ	Y				
	B11		210816	08/22/1		JP 🗸				N	Y (Abstract only)				
	B12	<u> </u>	36717	02/18/1		JP 🗸		/		N	N				
$\perp \perp$	B13		307974	10/30/1		ЛР 🗸	/			N	N				
$\perp \perp \mid$	B14		166724	07/02/1		JP 🗸				N	Y (Abstract only)				
	B15		177046	06/24/1		JP /				N	Y (Abstract only)				
	B16		244112	09/02/1		JP 🗸	\bot			Y	Y				
B17 6-252046 09/09/1994 /JP.										Y	Y				
	B18		94420	04/07/1		JP /				N	Y (Abstract only)				
	B19	<u> </u>	106446	04/21/1		JP ✓				N	N				
	B20	<u> </u>	240372	09/12/1		JP 🗸				N	Y (Abstract only)				
	B21		-270685	10/09/1		JP 🗸				N	Y				
V	B22	11.	-233744	08/27/1	999	JP V			 	N	N				
EXAMI	NER	<u>a</u>	Mal.	m_			DATE CONSIDERED (0/19/05								

FORM	РТО	- 14	49					ATTORNEY DOCKET NO.: ASC-066							
INFOR	MAT	ION	DISCLOS	URE S	ГАТЕ	EMENT		APF	LICANT	(S): Westl	hoff et al.				
								SER	LIAL NO.:	10/765,3	72				
				·								2823			
							FILING DATE: January 27, 2004 GROUP: 2812-								
					U.	S. PATE		T DOCUMENTS							
EXAM.			DOCUMEN	T	DAT	E	NA	ME	•	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
INIT.	-		NUMBER								CLASS	ATTAOTAGE			
		\dashv													
										\	<u> </u>				
		1 = :			roki	EIGN PA					A DOTTO 4 C	T ENGLISH AND			
EXAM INIT.		-	OCUMENT JMBER	DATE		COUN- TRY CODE	CL	ASS	SUB CLASS	FILING DATE	ABSTRAC ONLY	T ENGLISH LANG (Y/N)			
Som	B23.	61	-141116	06/28/1	986	JP /				-7	N	Y (Abstract only)			
2) 111	B24	20	00-021783	01/21/2	2000	JP 💉				/	N	Y			
	B25	20	00-031491	01/28/2	2000	JP /					N	Y			
	B26 2000-513507 10/10/2		10/10/2	2000	JP /				/	Y	N .				
	B27	20	01-319935	11/16/2	2001	JP /				/	N	Y			
	B28	20	02-076334	03/15/2	002	JP /			/		N	Y			
	B29	20	02-164520	06/07/2	2002	JP /			7		N	Y			
	B30	20	02-289533	10/04/2	002	JP /			7		N	Y			
	B31	20	02-356399	12/13/2	002	JP /					Y	· Y			
	B32	98	/59365	12/30/1	998	wo /					N	Y			
	B33	99	/53539	10/21/1	999	wo 🖊					N	Y			
	B34	00	/48239	08/17/2		wo /					N	Y			
	B35	00	/54338	09/14/2	2000	wo /					И	Y			
	B36	01	/022482	03/29/2	2001	wo 🗸					N	Y			
	B37	01	/54175	07/26/2		wo 🖊					N	Y			
	B38	L	/54202	07/26/2		wo /		$\bot I$			N	Y			
	B39	01	/93338	12/06/2		wo /		\int			N	Y			
	B40	<u> </u>	/99169	12/27/2		wo,/					N	Y			
	B41		/013262	02/14/2		wo 🗸					N	Y			
	B42		/015244	02/21/2		wo /					N	Y			
V	B43	02	/027783	04/04/2	2002	wo 🗸					N	Y			
EXAMI	XAMINER X BWalson								DATE CONSIDERED 05-19-05						

FO	RM	рто	- 1449					ΑŤ	TORNEY	DOCKET	NO.: ASC	C-066	
INI	FOR	MAT:	ION DISCLOS	URE S	TATI	EMENT		API	PLICANT	(S): West	hoff <i>et al</i> .		
								SEF	UAL NO.:	: 10/765,3	72	2000	
								FII	ING DAT	F· Ianuar	v 27 2004	<i>2823</i> GROUP: 2812 -	
					7.7	.S. PATE	NT						
EXA	M		DOCUMENT		DAT		NAI		UNIENI	CLASS	SUB	FILING DATE IF	
INIT			NUMBER	•	DAI	E	NAI	VIE		CLASS	CLASS	APPROPRIATE	
													
	~	1			_								
FOREIGN PATENT DOCUMENTS													
EXAM DOCUMENT DATE COUNTRY CODE CLASS SUB FILING ABSTRACT ENGLISH LANG CLASS DATE ONLY (Y/N)													
A	M _h	B44	02/047168	06/13/2	2002	wo	-			-	N	Y	
70	"	B45	02/071488	09/12/2	002	wo					N	Y	
		B46	02/071491	09/12/2	002	wo	-				N	Y	
		B47	02/071495 /	09/12/2	002	wo					N	Y	
		B48	02/082514 /	10/17/2	002	wo					N	Y	
		B49	03/015140 /	02/20/2	003	wo					Y (Abstract only)		
		B50	04/006311 /	01/15/2	004	wo					N	Y	
		B51	04/006327 /	01/15/2	004	wo					N	Y	
				OTH	ER A	ART, JOU	JRN	AL A	ARTICLE	ES, ETC.			
EXA INF		ОТ	HER DOCUME	NTS: (I	ncludi	ing Author	, Titl	e, Dat	e, Relevan	t Pages, Pl	ace of Publi	cation)	
R	λη	C2	Armstrong et a Transistors," I										
	`	C3	Institute of Te	chnology	, 199 <u>9</u>	9, pp. 1-154						is, Massachusetts	
		C4	MOD-MOSFE 254-258.	ETs with	out Io	n Implantati	ion,"	Thin_	Solid Films	, Vol. 294,	No. 1-2 (Fel	Complementary bruary 15, 1997), pp.	
		C5	channels for H	IMOS tra	nsisto	rs," <u>Moden</u>	n Phy	<u>sics l</u>	etters B, V	ol. 15 (200	1), abstract.	n, high Ge content SiGe	
C6 Borenstein et al., "A New Ultra-Hard Etch-Stop Layer for High Precision Micromachining," Proceedings of the 1999 12th IEEE International Conference on Micro Electro Mechanical Systems (MEMs) (January 17-21, 1999), pp. 205-210.													
`	V	C7	Bouillon et al. study," IEEE					el arc	hitecture fo	or 0.18/0.12	l μm bulk CN	MOS experimental	
EXA	MI	NER (About.	ar_			DA'	TE C	ONSIDER	ED	10/19	105	

FO	RM I	OTO	- 14	149					ATTORNEY DOCKET NO.: ASC-066					
IN.	FORM	/AT	O	N DISCLOS	URE S'	TATI	EMENT		API	PLICANT	(S): Westh	off et al.		•
									SEF	UAL NO.:	10/765,37	72		. 4022
									FIL	ING DAT	E: Januar	y 27, 2004	GR	<i>2823</i> OUP: 2812
_						U	.S. PATE	NT :	DOC	UMENT	S			
EX	AM.	<u> </u>		DOCUMENT	Γ	DAT	E	NA	ME		CLASS	SUB		LING DATE IF
INI	г .			NUMBER								CLASS	AI	PPROPRIATE
		<u> </u>					CICNI DA	7777	IT D	OOLD (E)	VITTO .		<u> </u>	
		FOREIGN PATENT DOCUMENTS DOCUMENT DATE COUN- CLASS SUB FILING ABSTRACT ENGLISH LANG												
EX.		NUMBER TRY CODE CLASS SUB FILING ABSTRACT ENGLISH LANG (Y/N)												
	十													
					OTH	ER A	ART, JOI	JRN	AL A	ARTICLE	ES, ETC.			
EX. INI	AM. T.	ОТ	HE	R DOCUME	NTS: (I	nclud	ing Author	, Titl	le, Da	te, Relevan	t Pages, Pl	ace of Public	cati	on)
å	874	C8 Bruel et al., "®SMART CUT: A Promising New SOI Material Technology," Proceedings of the 1995 IEEE International SOI Conference (October 1995), pp. 178-179.												
		C9		1201-1202.										ly 6, 1995), pp.
		C10		Bufler <i>et al</i> ., " Vol. 84, No. 1							1.yGey subs	trates," <u>Jour</u>	<u>ral c</u>	of Applied Physics,
	-	C11		Bulsara, "Mat MIT, June 19			ith the Inter	gratio	n of L	attice-Misr	natched In _x	Ga _{l-x} As on C	aA:	s," PhD Thesis,
		C12		Bulsara <i>at al</i> ., Applied Physi									hase	epitaxy on GaAs,"
		C13	'	Burghartz <i>et a</i> Technology," 100-104.										et Silicon January 1996), pp.
	·	C14			1 Silicon									fer Bonding and Issue 8 (August
		C15												ceed semiconductor (2002), abstract.
		C16		Carlin et al., " 2000 (2000), 1				-Si S	olar C	ells with Hi	gh Voc usi	ng Graded G	esi	Buffers," <u>IEEE –</u>
		C17 Carlin et al., "Investigation and Development of High Quality GaAs-on-Si for Space Photovoltaics Using a Graded GeSi," PhD Thesis, Ohio State University, 2001, pp. 1-232.												
	C18 Chang et al., "Selective Etching of SiGe/Si Heterostructures," <u>Journal of the Electrochemical Society</u> , No. 1 (January 1991), pp. 202-204.													
\	V	C19	- 1	pp. 1-4		Grow	th of GaAs	on Si	i at Th	omson," <u>IE</u>	E Colloqui	um on GaAs	on	<u>Si</u> , (8 Mar 1988),
EX	AMIN	er (Ä	Mal.	iar			DA'	TE C	ONSIDER	ED /	0/19/	25	> .

FORM 1	PTO -	1449					ΑT	FORNEY	DOCKET	'NO.: ASC	-060	6
INFOR	FOREIGN PATE STAM. NIT. DOCUMENT NUMBER FOREIGN PA EXAM DOCUMENT NUMBER OTHER ART, JO EXAM. OTHER DOCUMENTS: (Including Author (SGOI) Substrates," IEEE Electron De C21 Cheng et al., "Electron Mobility Enhant (SGOI) Substrates," IEEE Electron De C21 Cheng et al., "Relaxed Silicon-German Materials, Vol. 30, No. 12 (2001), pp. C22 Crumbaker et al., "The Influence of Di Physics Letters, Vol. 59, Issue 9 (08/2) C23 Cullis et al., "Growth ripples upon stra Journal of Vacuum Science and Techn C24 Currie et al., "Carrier mobilities and pr substrates," Journal of Vacuum Science C25 Currie et al., "Controlling Threading E Chemical-Mechanical Polishing," App C26 Currie, "SiGe Virtual Substrate Engine Systems and Strained Silicon Mosfets C27 Dilliway et al., "Characterization of M Journal of Materials Science, Vol. 11, C28 Eaglesham et al., "Dislocation-Free Str Vol. 64, No. 16 (April 16, 1990), pp. 1 C29 Erdtmann et al., "GalnAs/InP Quantum Plan Arrays," PhD Thesis, Northweste C30 Feichtinger et al., "Misfit Dislocation I Society, 148 (7) (2001), pp. G379-G38				EMENT		API	PLICANT	(S): Westh	noff et al.		
							SEF	UAL NO.:	10/765,37	72		0422
							 FIL	NG DAT	E: Januar	v 27. 2004	GR	•
				11	S DATE	NT		_				
EVAM	APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 JELING DATE: January 27, 2004 GROUP: 2842 U.S. PATENT DOCUMENTS AM. DOCUMENT NUMBER DATE NAME CLASS SUB CLASS FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS ABSTRACT NUMBER DOCUMENT NUMBER DATE COUNTRY CODE CLASS SUB FILING ABSTRACT COLLASS CLASS ABSTRACT COLLASS CLASS CLASS AMD OTHER ART, JOURNAL ARTICLES, ETC. OTHER ART, JOURNAL ARTICLES, ETC. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) C20 Cheng et al., "Electron Mobility Enhancement in Strained-Si n-MOSFET's Fabricated on SiGe-on-Insulator (SGOI) Substrates," IEEE Electron Device Letters, Vol. 22, No. 7 (July 2001), pp. 321-323. C21 Cheng et al., "Relaxed Silicon-Germanium on Insulator Substrate by Layer Transfer," Journal of Electronic Materials, Vol. 30, No. 12 (2001), pp. 137-139. C22 Crumbaker et al., "The Influence of Dislocation Density on Electron Mobility in InP Films on Si," Applied Physics Letters, Vol. 59, Issue 9 (08/26/91), pp. 1090-1092. C23 Cullis et al., "Growth ripples upon strained SiGe epitaxial layers on Si and misfit dislocation in interactions," Journal of Vacuum Science and Technology A, Vol. 12, No. 4 (July/August 1994), pp. 1924-1931. C24 Curric et al., "Carrier mobilities and process stability of strained Si n- and p-MOSFETs on SiGe virtual substrates," Journal of Vacuum Science and Technology B, Vol. 19, No. 6 (Nov/Dec 2001), pp. 2268-2279. C25 Curric et al., "Controlling Threading Dislocation Densities in Ge on Si Using Graded SiGe virtual substrates," Journal of Vacuum Science and Technology B, Vol. 19, No. 6 (Nov/Dec 2001), pp. 1718-1720. C26 Curric, "SiGe Virtual Substrate Engineering for Integration of III-V Materials, Microelectromechanical Systems and Strainad Silicon Mosfets with Silicon," PhD Thesis, MIT, 2001, pp. 1-190. C27 Dilliway et al., "Characterization of Morphology and Defects in Silicon Germanium Virtual Substrates," Journal of Materials Science, Vol. 11, Issue 7											
INIT.			•	DAI	£	INA	MIC		CLASS		ł	
-,-	APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 28.22 FILING DATE: January 27, 2004 GROUP: 2842- U.S. PATENT DOCUMENTS I. DOCUMENT NUMBER DATE NAME CLASS SUB FILING DATE IN APPROPRIATE FOREIGN PATENT DOCUMENTS II DOCUMENT NUMBER CLASS SUB FILING ABSTRACT ENGLISH LA (Y/N) OTHER ART, JOURNAL ARTICLES, ETC. II. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) C20 Cheng et al., "Electron Mobility Enhancement in Strained-Si n-MOSFETs Fabricated on SiGe-on-Insula (SGOI) Substrates," IEEE Electron Device Letters, Vol. 22, No. 7 (July 2001), pp. 321-323. C21 Cheng et al., "Relaxed Sition-Germanium on Insulator Substrate by Layer Transfer," Journal of Electro Materials, Vol. 30, No. 12 (2001), pp. 137-139. C22 Crumbaker et al., "The Influence of Dislocation Density on Electron Mobility in InP Films on Si," Appl Physics Letters, Vol. 39, Issue 9 (08/26/91), pp. 1090-1092. C23 Cullis et al., "Growth ripples upon strained SiGe epitaxial layers on Si and misfit dislocation interactions Journal of Vacuum Science and Technology A, Vol. 12, No. 4 (July/August 1994), pp. 1924-1931. C24 Currie et al., "Carrier mobilities and process stability of strained Si n- and p-MOSFETs on SiGe virtual substrates," Journal of Vacuum Science and Technology B, Vol. 19, No. 6 (Nov/Dec 2001), pp. 2268-22 C25 Currie et al., "Carrier mobilities and process stability of strained Si n- and p-MOSFETs on SiGe virtual substrates," Journal of Vacuum Science and Technology B, Vol. 19, No. 6 (Nov/Dec 2001), pp. 2268-22 C25 Currie, "SiGe Virtual Substrate Engineering for Integration of III-V Materials, Microelectromechanical Systems and Strained Silicon Mosfets with Silicon," PhD Thesis, MIT, 2001, pp. 1-190. C26 Currie, "SiGe Virtual Substrate Engineering for Integration of III-V Materials, Microelectromechanical Systems and Strained Silicon Mosfets with Silicon," PhD Thesis, MIT, 2001, pp. 1-190. C27 Currie et al., "GalnAs/InP Quantum Well Infrared Photodetectors on Si Substrate for Low-Cost F											
	APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 JELING DATE: January 27, 2004 GROUP: 2812- U.S. PATENT DOCUMENTS JOCUMENT NUMBER DATE NAME CLASS SUB CLASS FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS A DOCUMENT NUMBER DATE COUN- TRY CODE CLASS CLASS CLASS CLASS FILING ABSTRACT ONLY (Y/N) CONLY OTHER ART, JOURNAL ARTICLES, ETC. M. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) C1 C20 Cheng et al., "Electron Mobility Enhancement in Strained-Si n-MOSFETs Fabricated on SiGe-on-Insulator (SCOI) Substrates," IEEE Electron Device Letters, Vol. 22, No. 7 (July 2001), pp. 321-323. C1 C1 C1 C1 C1 C1 C1 C1 C1 C											
EXAM		•	DATE			CL	ASS .			i .	T	· '
INIT.		NUMBER			APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 JELING DATE: January 27, 2004 GROUP: 2842- U.S. PATENT DOCUMENTS DATE NAME CLASS CLASS SUB FILING DATE IF APPROPRIATE COREIGN PATENT DOCUMENTS COUNTRY CODE CLASS CLASS SUB FILING ABSTRACT CONLY TRY CODE CLASS CLASS CLASS FILING ABSTRACT ONLY (Y/N) CODE CHASS CLASS CLASS CLASS CHASS CLASS CHASS CLASS CLASS							
			_				•					
			ОТН	ER A	ART, JOU	JRN	AL A	ARTICLE	ES, ETC.			
EXAM. INIT.	ОТ	HER DOCUME	NTS: (I	ncludi	ing Author	, Titl	e, Da	te, Relevan	t Pages, Pl	ace of Publi	cati	on)
Am	C20											
1	C21							lator Subst	rate by Lay	er Transfer,"	Jou	mal of Electronic
	C22								ectron Mol	oility in InP	Film	s on Si," <u>Applied</u>
	C23											
	C24											
	C25	Chemical-Me	chanical l	Polish	ing," Appli	ed Pl	hysics	Letters, Vo	ol. 72, Issue	14 (04/06/9	8), p	ор. 1718-1720.
	C26											romechanical
	C27	Journal of Ma	terials Sc	ience,	Vol. 11, Is	sue 7	(200	0), pp. 549-	556.			
	C28							now Grow	th of Ge on	Si(100)," <u>Pl</u>	hysio	cal Review Letters,
	C29									Si Substrate	for l	Low-Cost Focal
	C30	1	-				tion S	tudy in p/p	+ Silicon,"	Journal of th	e El	ectrochemical
	C31	Etchback Silic	on-on-In	sulato	r," <u>Journal</u>	of El	ectror	ic Material	<u>s,</u> Vol. 23,	No. 6 (June	1994	4), pp. 493-496.
APPLICANT(S): Westhoff et al. SERIAL NO.: 10765,372 2823 FILING DATE: January 27, 2004 GROUP: -2842- U.S. PATENT DOCUMENTS EXAM. DOCUMENT NUMBER DATE NAME CLASS SUB FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS EXAM. NUMBER DATE COUNTRY CODE FILING DATE FILING DATE FOREIGN PATENT DOCUMENTS EXAM NUMBER DATE COUNTRY CODE FILING DATE FILING DATE FOREIGN PATENT DOCUMENTS EXAM OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) TITY COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) COTHER DOCUMENTS: (Including Device Letters, Vol. 24, No. 7 (Iuly 2001), pp. 213-233. COTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication, Place Date, Vol. 24, No. 16 (No. 16 Electronic Materials, Vol. 30, No. 12 (2001), pp. 1090-1092. COTHER DOCUMENTS: (Including Date Place of Plan Arrays, Place Date, Vol. 24, No. 16 (April 16, 1990), pp. 1994-1994. COTHER DOCUMENTS: (Including Date Place of Plan Arrays, Place Date, Vol. 11, Issue 7 (2000), pp. 149-556. COTHER DOCUMENTS: (Including Date Plan Arrays, Place Date Plan Arrays, Place Date P												
EXAMIN	EXAM. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) (C20 Cheng et al., "Electron Mobility Enhancement in Strained-Si n-MOSFETs Fabricated on SiGe-on-Insulator (SGOI) Substrates," IEEE Electron Device Letters, Vol. 22, No. 7 (July 2001), pp. 321-323. (C21 Cheng et al., "Relaxed Silicon-Germanium on Insulator Substrate by Layer Transfer," Journal of Electronic Materials, Vol. 30, No. 12 (2001), pp. L37-L39. (C22 Crumbaker et al., "The Influence of Dislocation Density on Electron Mobility in InP Films on Si," Applied Physics Letters, Vol. 59, Issue 9 (08/26/91), pp. 1090-1092. (C23 Cullis et al., "Growth ripples upon strained SiGe epitaxial layers on Si and misfit dislocation interactions," Journal of Vacuum Science and Technology A, Vol. 12, No. 4 (July/August 1994), pp. 1924-1931. (C24 Currie et al., "Carrier mobilities and process stability of strained Si n- and p-MOSFETs on SiGe virtual substrates," Journal of Vacuum Science and Technology B, Vol. 19, No. 6 (Nov/Dec 2001), pp. 2268-2279. (C25 Currie et al., "Controlling Threading Dislocation Densities in Ge on Si Using Graded SiGe Layers and Chemical-Mechanical Polishing," Applied Physics Letters, Vol. 72, Issue 14 (04/06/98), pp. 1718-1720. (C26 Currie, "SiGe Virtual Substrate Engineering for Integration of III-V Materials, Microelectromechanical Systems and Strained Silicon Mosfets with Silicon," PhD Thesis, MIT, 2001, pp. 1-190. (C27 Dilliway et al., "Characterization of Morphology and Defects in Silicon Germanium Virtual Substrates," Journal of Materials Science, Vol. 11, Issue 7 (2000), pp. 549-556. (C28 Eaglesham et al., "Dislocation-Free Stranski-Krastanow Growth of Ge on Si(100)," Physical Review Letters, Vol. 64, No. 16 (April 16, 1990), pp. 1943-1946. (C30 Feichtinger et al., "Misfit Dislocation Nucleation Study in p/p+ Silicon," Journal of the Electrochemical Society, 148 (7) (2001), pp. G379-G382. (C31 Feichti											

FORM	PTO -	1449		•			AT	TORNEY	DOCKET	NO.: ASC	-06	6
INFOR	MATI	ON DISCLOS	SURE S	TATI	EMENT		API	PLICANT	(S): Westh	off et al.		
							SEF	LIAL NO.:	10/765,37	72		00
							FIL	ING DAT	E: Januar	v 27. 2004	GR	<i>2823</i> ROUP: 2812 -
	-			17	.S. PATE	NIT	<u> </u>					
EXAM.	1	DOCUMEN	т	DAT		NA		OWILNI	CLASS	SUB	F	ILING DATE IF
INIT.		NUMBER	•	"	L		.,,,,			CLASS		PPROPRIATE
												·
				FOR	EIGN PA	TEN	VT D	OCUME	NTS			_
EXAM		DOCUMENT	DATE		COUN-	CL	ASS	SUB	FILING	ABSTRAC	T	ENGLISH LANG
· INIT.		NUMBER			TRY CODE			CLASS	DATE	ONLY		(Y/N)
									l			
			OTF	IER A	ART, JOI	JRN	IAL A	ARTICLE	ES, ETC.			
EXAM. INIT.	OTH	IER DOCUME	ENTS: (I	nclud	ing Author	, Titl	le, Dat	te, Relevan	t Pages, Pi	ace of Publi	cati	on)
Som	C33	Fischetti, "Lo oxide structur										onmobility in thin- 2-1250.
1	C34	Fitzgerald, "I Reports, Vol.				er ep	itaxy:	theory, exp	eriment, an	d application	15,"	Materials Science
	C35		al., "Disl	ocatio	n dynamics		laxed	graded com	position se	miconductor	s,"]	Materials Science
	C36	Fitzgerald et a					Depart	ment of Ma	terials Scie	nce, M.I.T.,	(199	95), pp. 1-15.
	C37	Fitzgerald et e								and high mo	bili	ity two-dimensional
	C38	Fitzgerald et a Substrates," A)en:	sities Grown on Si
	C39	Garone et al., Letters, Vol.							y the prese	nce of germa	апе,	" Applied Physics
	C40	Giovane et al. Optical Interc							s for Near I	R Photodete	ctio	n in Silicon-Based
	C41	Godbey et al., Etch Stop," Jo										0.7GE0.3 Layer as an 223.
	C42											34, pp. 605-632.
	C43	Physics, Vol.	91, No. 8	3 (Apr	il 15, 2002)	, pp.	4891-	4899.				Journal of Applied
	C44	Groenert et al on Ge/GeSi/S Symposium P	i Substra	tes Vi	a Relaxed C	Grade	d Ge _x S	Si(1-x) Buffe	r Layers,"			LEDS and Lasers rch Society
	C45											position technique p. 2531-2533.
V	C46	Hackbarth et a 2 (July 2000),			s to thick !	MBE-	growi	relaxed Si	Ge buffers,	" <u>Thin Solid</u>	Fil	ms, Vol. 369, No. 1-
EXAMIN	VER /	Abril.	mu-			DA'	TE C	ONSIDER	ED /	0/19/	0.4	5

FORM I	TOTHER ART, J OTHER DOCUMENTS: (Including Aut C47 Hackbarth et al., "Strain relieved Siden Crystal Growth, Vol. 201/202 (1999) C48 Halsall et al., "Electron diffraction a the AiGalnP sysstem," Journal of Ag C49 Herzog et al., "SiGe-based FETs: but 36-41. C50 Höck et al., "Carrier mobilities in many plications," Thin Solid Films, Vol. C51 Höck et al., "High hole mobility in Segrown by plasma-enhanced chemical 2000), pp. 3920-3922. C52 Höck et al., "High performance 0.25 (September 17, 1998), pp. 1888-188 C53 Houghton, "Strain Relaxation Kinetin No. 4 (August 15, 1991), pp. 2136-2 C54 Hsu et al., "Near Field Scanning Opt Devices," Materials Science and Eng						AT	TORNEY	DOCKET	NO.: ASC	-06	6
INFORM	/ATI	ON DISCLOS	U.S. PATENT UMENT BER FOREIGN PATE FOREIGN PATE COUNTRY CODE OTHER ART, JOUR CUMENTS: (Including Author, T Outh et al., "Strain relieved SiGe buff Growth, Vol. 201/202 (1999), pp. 7 et al., "Electron diffraction and Ran GalnP sysstem," Journal of Applied I et al., "SiGe-based FETs: buffer is t al., "Carrier mobilities in modulati tions," Thin Solid Films, Vol. 336 (t al., "High hole mobility in Si _{0.17} Go by plasma-enhanced chemical vapor pp. 3920-3922. t al., "High performance 0.25 µm p- nber 17, 1998), pp. 1888-1889. con, "Strain Relaxation Kinetics in S August 15, 1991), pp. 2136-2151. al., "Near Field Scanning Optical M				API	PLICANT	(S): Westh	off et al.		
							SER	UAL NO.:	10/765,37	72		2627
							FIL	ING DAT	E: Januar	y 27, 2004	GR	<i>2823</i> OUP: - 2812 -
	· • · • • · ·			IJ	S PATE	NT	DOC	UMENT	S			
EXAM.		DOCUMEN	 Т			NA			CLASS	SUB	FI	LING DATE IF
INIT.		NUMBER								CLASS	A	PPROPRIATE
						· _						······
	······································			FOR	EIGN PA	TEN	T D	OCUME	NTS	<u></u>		
EXAM INIT.		•	DATE		TRY	CL	ASS	SUB CLASS	FILING DATE	ABSTRAC ONLY	Т	ENGLISH LANG (Y/N)
									-			
	•		OTF	ER A	ART, JOU	JRN	AL A	ARTICLE	ES, ETC.			
EXAM. INIT.	ОТІ	HER DOCUME	NTS: (I	nclud	ing Author	, Titl	e, Dat	te, Relevan	t Pages, Pi	ace of Publi	cati	on)
Alm	C47								terostructur	e field-effec	t tra	nsistors," <u>Journal of</u>
1	C48											
	C49		"SiGe-b	ased F	ETs: buffe	r issu	es and	device res	ults," Thin	Solid Films,	Vo	l. 380 (2000), pp.
	C50	applications,"	Thin So	<u>lid Fil</u>	<u>ms</u> , Vol. 33	6 (19	98), p	р. 141-144				
	C51	grown by plas	ma-enha	nced c								
	C52	(September 1	7, 1998),	pp. 18	888-1889.							
		No. 4 (August	15, 199	1), pp.	2136-2151	١		•		_		
	C54											
	C55				ogy of relat	ed G	e _x Si _{1-x}	films," App	plied Physic	cs Letters, 61	(1)	1) (September 14,
	C56										ated	by wafer bonding",
	C57									silicon-on-i	nsul	ator substrate,"
	C58	Huang et al., Solid-State Ci								S RF Circuit	s," <u>I</u>	EEE Journal of
	C59	Ishikawa et al Proceedings o										ntation,"
EXAMIN	ER (To Mal	saw		_	DA	TE C	ONSIDER	ED /	0/19	10	75

FOREIGN PA EXAM DOCUMENT NUMBER FOREIGN PA EXAM DOCUMENT NUMBER OTHER ART, JOU EXAM. OTHER DOCUMENTS: (Including Author, INIT. C60 Ishikawa et al., "SiGe-on-insulator substates and Technology No. 10 (September 5, 1994), pp. 1248-11 C61 Ismail et al., "Modulation-doped n-type No. 10 (September 5, 1994), pp. 1248-11 C62 Ismail, "Si/SiGe High-Speed Field-Effect (December 10, 1995), pp. 20.1.1-20.1.4. C63 Kearney et al., "The effect of alloy scatter Semiconductor Science and Technology C64 Kim et al., "A Fully Integrated 1.9-GHz Letters, Vol. 8, No. 8 (August 1998), pp. C65 Kissinger, et al. "Stepwise Equilibrated Density on Si(001)," Applied Physics Letters, Vol. 8, No. 8 (August 1998), pp. C66 Knall et al., "The Use of Graded in GaA Dislocations From GaAs on Si," Journal 2702. C67 Koester et al., "Extremely High Transco Electron Device Letters, Vol. 21, No. 3 (C68 König et al., "Design Rules for n-Type Spp. 1541-1547.				AT	FORNEY	DOCKET	NO.: ASC	-066	6			
INFORMATION DISCLOSURE STATEMENT U.S. PAT EXAM. INIT. DOCUMENT NUMBER FOREIGN FOREIGN EXAM INIT. OTHER ART, J EXAM. OTHER DOCUMENTS: (Including Autilinity) INIT. C60 Ishikawa et al., "SiGe-on-insulator s 75, No. 7 (August 16, 1999), pp. 983 C61 Ismail et al., "Modulation-doped n-t No. 10 (September 5, 1994), pp. 124 C62 Ismail, "Si/SiGe High-Speed Field-E (December 10, 1995), pp. 20.1.1-20. C63 Kearney et al., "The effect of alloys s Semiconductor Science and Technol C64 Kim et al., "A Fully Integrated 1.9-C Letters, Vol. 8, No. 8 (August 1998), Density on Si(001)," Applied Physic C65 Kissinger, et al. "Stepwise Equilibra Density on Si(001)," Applied Physic C66 Knall et al., "The Use of Graded in C Dislocations From GaAs on Si," Jou 2702. C67 Koester et al., "Extremely High Tran Electron Device Letters, Vol. 21, No C68 König et al., "Design Rules for n-Ty pp. 1541-1547. C69 König et al., "P-Type Ge-Channel M Electron Device Letters, Vol. 14, No C70 König et al., "SiGe HBTs and HFET C71 Kummer et al., "Low energy plasma			EMENT		APF	PLICANT	(S): Westh	off et al.				
							SER	UAL NO.:	10/765,37	72		20.00
							EII .	ING DAT	F. Januar	v 27 2004	GR	2,00
					\		L	<u> </u>		y 27, 2004		
	APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 J823 FILING DATE: January 27, 2004 GROUP: 2812 U.S. PATENT DOCUMENTS AM. DOCUMENT NUMBER DATE NAME CLASS SUB FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS CAM. NUMBER DOCUMENT DATE COUNCLASS SUB FILING ABSTRACT ENGLISH LANG CLASS TRY CODE OTHER ART, JOURNAL ARTICLES, ETC. CAM. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) IIT. C60 Ishikawa et al., "SiGe-on-insulator substrate using SiGe alloy grown Si(001)," Applied Physics Letters. Vol. 75, No. 7 (August 16, 1999), pp. 983-985. C61 Ismail et al., "Modulation-doped n-type Si/SiGe with inverted interface," Applied Physics Letters. Vol. 8, No. 10 (September 5, 1994), pp. 1248-1250. C62 Ismail, "Si/SiGe High-Speed Field-Effect Transistors," Electron Devices Meeting, Washington, D.C. (December 10, 1995), pp. 201.1-20.1-14. C63 Kearney et al., "The effect of alloy scattering on the mobility of holes in a Si _{1-x} Ge, quantum well," Semiconductor Science and Technology, Vol. 13 (1998), pp. 174-180. C64 Kim et al., "The Filly Integrated 1 9-GHz CMOS Low-Noise Amplifier," IEEE Microwave and Guided Wave Letters, Vol. 8, No. 8 (August 1998), pp. 293-295. C65 Kissinger, et al. "Stepwise Equilibrated Graded Ge, Si _{1-x} Buffer With Very Low Threading Dislocation From GaAs on Si," Journal of Applied Physics, Vol. 76, Issue 5 (September 1, 1994), pp. 2697-2702. C67 Koester et al., "Extremely High Transconductance Ge/Si _{2x} Ge _{0x} P-MODFET's Grown by UHV-CVD," IEEE											
			Γ	DAT	E	NA.	ME		CLASS		1	
	SERIAL NO.: 10/765,372 JELING DATE: January 27, 2004 GROUP: 2812 U.S. PATENT DOCUMENTS DOCUMENT NUMBER DATE NAME CLASS SUB FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS DOCUMENT DATE COUNCIDENTS DOCUMENT DATE COUNCIDENTS DOCUMENT TRY CODE OTHER ART, JOURNAL ARTICLES, ETC. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) C60 Ishikawa et al., "SiGe-on-insulator substrate using SiGe alloy grown Si(001)," Applied Physics Letters, Vol. 75, No. 7 (August 16, 1999), pp. 983-983. C61 Ismail et al., "Modulation-doped n-type Si/SiGe with inverted interface," Applied Physics Letters, Vol. 65, No. 10 (September 5, 1994), pp. 1248-1230. C62 Ismail, "Si/SiGe High-Speed Field-Effect Transistors," Electron Devices Meeting, Washington, D.C. (December 10, 1995), pp. 201.1-20.1.4. C63 Kearney et al., "The effect of alloy scattering on the mobility of holes in a Si _{1-x} Ge _x quantum well," Semiconductor Science and Technology, Vol. 13 (1998), pp. 174-180. C64 Kissinger, et al. "Stepwise Equilibrated Graded Ge, Si _{1-x} , Buffer With Very Low Threading Dislocation Density on Si(001)," Applied Physics Letters Vol. 66, No. 16 (Apr. 17, 1995), pp. 2083-2085. C65 Kissinger, et al. "Stepwise Equilibrated Graded Ge, Si _{1-x} , Buffer With Very Low Threading Dislocations From GaAs on Si," Journal of Applied Physics, Vol. 76, Issue 5 (September 1, 1994), pp. 2697-2702. C67 Koester et al., "Extremely High Transconductance Ge/Si ₂ A, Ge _{0.6} p-MODFET's Grown by UHV-CVD," IEEE Electron Device Letters, Vol. 21, No. 3 (March 2000), pp. 110-112.											
	U.S. PATENT DOCUMENTS DOCUMENT NAME CLASS SUB FILING DATE IF APPROPRIATE											
EXAM		DOCUMENT	DATE		COUN-	CL	ASS	SUB	FILING	ABSTRAC	Т	ENGLISH LANG
INIT.		NUMBER					APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 FILING DATE: January 27, 2004 GROUP: 28+2- NT DOCUMENTS NAME CLASS SUB CLASS SUB FILING DATE IF APPROPRIATE TENT DOCUMENTS CLASS SUB CLASS SUB FILING ABSTRACT CLASS SUB CLASS SUB FILING ABSTRACT CLASS SUB FILING ONLY (Y/N) FILING ONLY CLASS CLASS SUB FILING ABSTRACT CLASS CLASS SIB FILING ABSTRACT CLASS CLASS SIGUATE APPROPRIATE ENGLISH LANG (Y/N) CLASS SI/SiGe with inverted interface," Applied Physics Letters, Vol. 65, 250. CT Transistors," Electron Devices Meeting, Washington, D.C. CROST LOW-Noise Amplifier," IEEE Microwave and Guided Wave 293-295. Graded Ge,Si _{1-x} Buffer With Very Low Threading Dislocation enters Vol. 66, No. 16 (Apr. 17, 1995), pp. 2083-2085. S Layers and Patterned Substrates to Remove Threading of Applied Physics, Vol. 76, Issue 5 (September 1, 1994), pp. 2697- Inductance Ge/Si _{0,4} Ge _{0,6} p-MODFET's Grown by UHV-CVD," IEEE March 2000), pp. 110-112. GIGE Hetero FETs," Solid State Electronics, Vol. 41, No. 10 (1997), FET's with High Transconductance Grown on Si Substrates," IEEE					
	APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 2823 FILING DATE: January 27, 2004 GROUP: 2842 U.S. PATENT DOCUMENTS EXAM. DOCUMENT DATE NAME CLASS SUB FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS EXAM DOCUMENT DATE COUNTRY CODE FILING ABSTRACT ENGLISH LANG (V/N) OTHER ART, JOURNAL ARTICLES, ETC. EXAM. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) NIT. C60 Ishikawa et al., "SiGe-on-insulator substrate using SiGe alloy grown Si(001)," Applied Physics Letters, Vol. 75, No. 7 (August 16, 1999), pp. 983-985. C61 Ismail et al., "Modulation-doped n-type Si/SiGe with inverted interface," Applied Physics Letters, Vol. 65, No. 10 (September 5, 1994), pp. 1248-1250. C62 Ismail, "Si/SiGe High-Speed Field-Effect Transistors," Electron Devices Meeting, Washington, D.C. (December 10, 1995), pp. 20.1.1-20.1.4. C63 Kearney et al., "The effect of alloy scattering on the mobility of holes in a Si _{1-x} Ge, quantum well," Semiconductor Science and Technology, Vol. 13 (1998), pp. 174-180. C64 Kim et al., "A Fully Integrated 19-GHz CMOS Low-Noise Amplifier," IEEE Microwave and Guided Wave Letters, Vol. 8, No. 8 (August 1998), pp. 293-295. C65 Kissinger, et al. "Stepwise Equilibrated Graded Ge, Si _{1-x} Buffer With Very Low Threading Dislocation Density on Si(001)," Applied Physics Isters Vol. 66, No. 16 (Apr. 17, 1995), pp. 2083-2085. C66 Knall et al., "The Use of Graded in GaAs Layers and Patterned Substrates to Remove Threading Dislocations From GaAs on Si," Journal of Applied Physics, Setter Vol. 67, Issue 5 (September 1, 1994), pp. 2697-2702. C67 Koester et al., "Extremely High Transconductance GerSi ₆ Age ₆₋₆ PMODFET's Grown by UHV-CVD," IEEE Electron Device Letters, Vol. 14, No. 10 (1997), pp. 1541-1547. C69 König et al., "Posign Rules for n-Type SiGe Hetero FETs," Solid State Electronics, Vol. 41, No. 10 (1997), pp. 1541-1547.											
			OTH	IER A	ART, JOI	JRN	IAL A	ARTICLI	ES, ETC.	<u> </u>		
	ОТ	HER DOCUME	NTS: (I	nclud	ing Author	, Tit	le, Dat	te, Relevan	t Pages, Pi	ace of Publi	cati	on)
Sim	C60						using	SiGe alloy	grown Si(0	01)," Appli	ed P	hysics Letters, Vol.
1	C61							ith inverted	interface,"	Applied Phy	ysics	s Letters, Vol. 65,
	C62	Ismail, "Si/Si (December 10	Ge High-), 1995),	Speed pp. 20	Field-Effe .1.1-20.1.4	ct Tra	ansisto	ors," Electro	n Devices	Meeting, Wa	shir	ngton, D.C.
	C63									si _{1-x} Ge _x qu	antu	m well,"
	C64							w-Noise A	mplifier," <u>I</u>	EEE Microv	ave	and Guided Wave
	C65	Kissinger, et of Density on Si	al. "Step (001)," <u>A</u>	wise E Applie	quilibrated d Physics L	Grac etters	ied Ge s Vol.	_x Si _{1-x} Buffe 66, No. 16	r With Ver (Apr. 17, 1	y Low Threa 995), pp. 20	adinį 83-2	g Dislocation 2085.
	C66	Dislocations										
	C67									ET's Grown	by	UHV-CVD," <u>IEEE</u>
	C68			Rules	for n-Type	SiGe	Hetero	o FETs," <u>S</u>	olid State E	lectronics, V	'ol. '	41, No. 10 (1997),
	C69									nce Grown o	n Si	Substrates," <u>IEEE</u>
	C70											
	C71	Kummer et al Engineering,				nance	d cher	nical vapor	deposition	," <u>Materials</u>	Scie	ence and
V	C72											
EXAMIN	ER	Phylles	van			DA	TE C	ONSIDER	ED /	0/19/0	5	-

FO	RM P	то -	- 1449				I	AT	FORNEY	DOCKET	NO.: ASC	-060	6
INF	ORM	1ATI	ON DISCLOS	URE S	TATI	EMENT		API	PLICANT	(S): Westh	ioff et al.		
							1	SEF	RIAL NO.:	: 10/765,37	72		
							1					GR	<i>2823</i> ROUP: 2812 -
			 			O DATE		J			y 21, 200		
			DOCUMEN		DAT			ME	UMENI	·	CIID	T	T BIO DATE IE
EXA INIT.			DOCUMENT NUMBER	<u> </u>	DAI	'E	NA	.ME		CLASS	CLASS		
<u> </u>		<u> </u>			<u></u>		<u> </u>		UMENTS CLASS SUB FILING DATE IF APPROPRIATE CLASS DATE ONLY ENGLISH LANG (Y/N) ARTICLES, ETC. e, Relevant Pages, Place of Publication) ng," Applied Physics Letters, Vol. 76, Issue 25 (June 19, ree Strained Si on Insulator Substrates" IEEE International RFIC's Present Status and Future Directions," IEEE ch 1998), pp. 387-399. and Beyond," Proceedings of the IEEE, Vol. 88, No. 10				
				•	FOR	1		_	OCUME		T		Y
EXA INIT			DOCUMENT NUMBER	DATE		COUN- TRY CODE	CL	ASS	1	1		T	
				OTF	ER.	ART, JOI	URN	IAL A	ARTICLE	ES, ETC.			
EXA INIT		ОТІ	HER DOCUME	NTS: (I	includ	ing Author	, Titl	le, Da	te, Relevan	t Pages, Pl	ace of Public	cati	on)
de	m	C73	2000), pp. 370	00-3702.									
		C74	SOI Conferen	ice, pages	s 211-	212 (XP002	22630	057)					
		C75	Journal of Sol	lid-State	Circui	its, Vol. 33,	, No. :	3 (Ma	rch 1998), p	pp. 387-399	9.		-
		C76	(October 2000	0), pp. 15	560-15	571.							
		C77	xGex/Si virtua	al substra	ates," į	Applied Phy	<u>ysics</u>	Letter	<u>s,</u> Vol. 79, 1	No. 20 (No	vember 12, 2	2001	l), pp. 3344-3346.
		C78	Research Soci	iety Sym	posiun	m Proceedin	ngs, V	Vol. 68	86 (2002), p	p. A1.9.1-A	A1.9.5.		
		C79	Vol. 75, Issue	: 11 (June	e 1, 19	974), pp. 27	30-27	738.					
		C80	Research Soci	iety Sym	posiun	n Proceedin	ngs, V	Vol. 68	36 (2002), p	p. A3.10.1-	-A3.10.6.		
		C81	Leitz et al., "I Physics, Vol.								raded SiGe/S	ši," ;	Journal of Applied
		C82		orș growi	n on re	elaxed Sil-x	xGex						
		C83		th reduce	d shor	rt-channel e							
	V	C84									ayers for 1.5	5-μ	M Photodetector
EXA	MINI	ER /	X CoMal	sam			DA	TE C	ONSIDER	ED /	10/19/	10	5

FOR	M P	TO ·	1449					AT	TORNEY	DOCKET	'NO.: ASC	-06	6	
INFO	TOTHER ART, JO Cas Liu et al., "High-Quality Ge Films on Sapplied Physics Letters, Vol. 75, No. 19 (November 8, Luo et al., "High-Quality Ge epilayer Letters, Vol. 75, No. 19 (November 8, Luo et al., "High-Quality Strain-Relax Applied Physics, Vol. 89, Issue 13 (See Cas Maiti et al., "Strained-Si heterostructur Vol. 13 (1998), pp. 1225-1246. C90 Maszara, "Silicon-On-Insulator by Wa (January 1991), pp. 341-347. C91 Meyerson et al., "Cooperative Growth Applied Physics Letters, Vol. 53, No. 2 C92 Mizuno et al., "Advanced SOI-MOSFI Mobility Enhancement," 2002 Sympos pp. 210-211. C93 Mizuno et al., "Electron and Hole Mot Substrates Fabricated by SIMOX Tech 230-232.			EMENT		API	PLICANT	(S): Westh	noff et al.		·			
								SEF	UAL NO.:	10/765,37	72		•	
								FIL	ING DAT	E: Januar	y 27, 2004	GR	• .	
					U	S. PATE	NT	DOC	UMENT	S				
EXAM INIT.	ſ.			r	DAT	E	NA	ME		CLASS	SUB CLASS			
									·					
	U.S. PAT DOCUMENT NUMBER FOREIGN F OTHER ART, JO OTHER DOCUMENTS: (Including Auth Applied Physics Letters, Vol. 79, Issue 13 (See 1) C85 Liu et al., "High-Quality Ge Films on Applied Physics Letters, Vol. 79, Issue 13 (See 1) C86 Lu et al., "High Quality Ge epilayon Letters, Vol. 75, No. 19 (November 8) C87 Luan, et al. "High Quality Ge epilayon Letters, Vol. 75, No. 19 (November 8) C88 Luo et al., "High-Quality Strain-Rela Applied Physics, Vol. 89, Issue 13 (See 1) C89 Maiti et al., "Strained-Si heterostructure Vol. 13 (1998), pp. 1225-1246. C90 Maszara, "Silicon-On-Insulator by Word (January 1991), pp. 341-347. C91 Meyerson et al., "Cooperative Growth Applied Physics Letters, Vol. 53, No. Mobility Enhancement," 2002 Sympology 210-211. C93 Mizuno et al., "Advanced SOI-MOSH Mobility Enhancement," 2002 Sympology 210-211. C93 Mizuno et al., "Electron and Hole Mosubstrates Fabricated by SIMOX Tec 230-232. C94 Mizuno et al., "High Performance Str SIMOX Technology," IEEE IDEM To 936. O C95 Momose et al., "Dislocation-Free and Pole Mosubstrates Pabricated Pole Mo					EIGN PA	TEN	NT D	OCUME	NTS	•			
	U.S. PATENT DOCUMENTS EXAM. DOCUMENT DATE NAME CLASS SUB CLASS APPROPRIATE FOREIGN PATENT DOCUMENTS EXAM DOCUMENT DATE NAME CLASS SUB FILING DATE APPROPRIATE DOCUMENT DATE COUN CLASS SUB FILING ABSTRACT ENGLISH L (Y/N) CODE CLASS DATE ONLY (Y/N) CODE CLASS DATE ONLY (Y/N) CODE CLASS DATE ONLY (Y/N) CODE CLASS CLASS DATE ONLY (Y/N) CODE CLASS CLASS DATE ONLY (Y/N) CODE CLASS C								ENGLISH LANG					
INIT.			NUMBER						CLASS	DATE	ONLY		(Y/N)	
										ANT(S): Westhoff et al. NO.: 10/765,372 2823 DATE: January 27, 2004 GROUP: 2812- ENTS CLASS SUB FILING DATE IF APPROPRIATE JMENTS B FILING ABSTRACT ENGLISH LANG (Y/N) TCLES, ETC. elevant Pages, Place of Publication) 19 SB Surfactant-Mediated Graded SiGe Buffers," 19, 2001), pp. 3431-3433. 10 SiGe MODFET's and MOS-MODFET's," IEEE 1st 2000), pp. 1645-1652. Areading-dislocation densities," Applied Physics 2911. 10 own with Low Temperature Si Buffer," Journal of (Y), pp. 1611-1613. 11 Sistors," Semiconductor Science and Technology, 1988), pp. 2555-2557. 12 Si Channel for High Speed CMOS-Electron/Hole chnology, Honolulu (June 13-15), IEEE New York, 1981, pp. 2555-2557. 13 Strained-Si MOSFET's on SiGe-on-Insulator 1981 (May 2000), pp. 101 (May 20				
				OTH	IER A	ART, JOI	JRN	IAL A	ARTICLE	ES, ETC.				
	1.	ОТ	HER DOCUME	NTS: (I	nclud	ing Author	, Titl	le, Da	te, Relevan	t Pages, Pl	ace of Publi	cati	on)	
dir	M	C85										ade	d SiGe Buffers,"	
1		C86										S-M	ODFET's," <u>IEEE</u>	
		C87								ng-dislocati	on densities,	." <u>A</u>	pplied Physics	
		C88										i Bu	ıffer," <u>Journal of</u>	
		C89					field	effec	t transistors	," <u>Semicon</u>	ductor Scien	ice a	and Technology,	
		C90					r Bo	nding	A Review	," <u>Journal c</u>	of the Electro	oche	mical Society, No. 1	
		C91	Applied Physi	cs Letter	s, Vol	. 53, No. 25	5 (De	cembe	er 19, 1988)	, pp. 2555-	2557.		•	
		C92	Mobility Enha											
		C93	Substrates Fal											
		C94	SIMOX Techi 936.	nology,"	IEEE	IDEM Tecl	hnica	l Dige	<u>st</u> (1999 Int	ternational	Electron Dev	vice	Meeting), pp. 934-	
$\overline{\Psi}$	′	C95												
EXAM	IINE	ER /	X MMel	· ·			DA	TE C	ONSIDERI	ED	10/19	10:	5_	

FOR	M I	OT	- 14	149					ΑТ	TORNEY	DOCKET	NO.: ASC	-06	6
INF	ORN	/IAT	OI	N DISCLOS	URE S'	TATI	EMENT		API	PLICANT	(S): Westh	off et al.		
									SEF	UAL NO.:	10/765,37	72		2
									FIL	ING DAT	E: Januar	y 27, 2004	GR	
						U	.S. PATE	NT	DOC	UMENT	S			
EXAI INIT.	м.	FOREIGN DOCUMENT DATE NUMBER OTHER ART, J OTHER DOCUMENTS: (Including Aut C96 Monroe et al., "Comparison of Mob Journal of Vacuum Science and Tecl C97 Nayak et al., "High-Mobility Straine 10 (October 1996), pp. 1709-1716. C98 Oh et al., "Interdigitated Ge p-i-n Ph Layers," IEEE – Journal of Quantum C99 Ohori et al., "Effect of Threading Di Si Substrates," Journal of Applied Pl C100 O'Neill et al., "SiGe virtual substrate Technology, Vol. 14 (1999), pp. 784 C101 Ota, "Application of heterojunction I 30, No. 11(May 26, 1994), pp. 906-5 C102 Papananos, "Radio-Frequency Micro Academic Publishers, 1999, pp. 115- C103 Parker et al., "SiGe heterostructure C pp. 1497-1506. C104 Powell et al., "New Approach to the Letters, Vol. 64, Issue 14 (April 4, 1				E	NA	ME		CLASS	SUB CLASS	ı	•	
	FORE TO NUMBER FORE TO NUMBER OTHER A AM. OTHER DOCUMENTS: (Including and a second and a s													
						FOR	EIGN PA	TEN	T D	OCUME	NTS			
ŀ	- 1	•	i	1	DATE		COUN- TRY CODE	CL	ASS	SUB CLASS	FILING DATE	ABSTRAC ONLY	T	ENGLISH LANG (Y/N)
	1		_		E	FOREIGN PATENT DOCUMENTS TE COUNTRY CLASS SUB FILING DATE ONLY (Y/N) THER ART, JOURNAL ARTICLES, ETC. (Including Author, Title, Date, Relevant Pages, Place of Publication) Imparison of Mobility-Limiting Mechanisms in High-Mobility Si _{1-x} Ge _x Heterostructures," Science and Technology B, Vol. B11, Issue 4 (Jul/Aug 1993), pp. 1731-1737. -Mobility Strained-Si PMOSFET's," IEEE Transactions on Electron Devices, Vol. 43, No. pp. 1709-1716. Itated Ge p-i-n Photodetectors Fabricated on a Si Substrate Using Graded SiGe Buffer urnal of Quantum Electronics, Vol. 38, Issue 9 (Sept 2002), pp. 1238-1241. It of Threading Dislocations on Mobility in Selectively Doped Heterostructures Grown on mal of Applied Physics, Vol. 75, Issue 7 (April 1, 1994), pp. 3681-3683. Te virtual substrate N-channel heterojunction MOSFETS," Semiconductor Science and 4 (1999), pp. 784-789.								
	FOREIGN PATENT DOCUMENTS EXAM DOCUMENT DATE COUNTRY CODE OTHER ART, JOURNAL ARTICLES, ETC. EXAM. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) NIT. C96 Monroe et al., "Comparison of Mobility-Limiting Mechanisms in High-Mobility Si _{1-x} Ge, Heterostructures," Journal of Vacuum Science and Technology B, Vol. B11, Issue 4 (Jul/Aug 1993), pp. 1731-1737. C97 Nayak et al., "High-Mobility Strained-Si PMOSFET's," IEEE Transactions on Electron Devices, Vol. 43, No. 10 (October 1996), pp. 1709-1716. C98 Oh et al., "Interdigitated Ge p-i-n Photodetectors Fabricated on a Si Substrate Using Graded SiGe Buffer Layers," IEEE – Journal of Quantum Electronics, Vol. 38, Issue 9 (Sept 2002), pp. 1238-1241. C99 Ohori et al., "Effect of Threading Dislocations on Mobility in Selectively Doped Heterostructures Grown on Si Substrates," Journal of Applied Physics, Vol. 75, Issue 7 (April 1, 1994), pp. 3681-3683.													
FOREIGN PATENT DOCUMENTS EXAM NUMBER DATE COUNTRY OTHER ART, JOURNAL ARTICLES, ETC. EXAM. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) INIT. C96 Monroe et al., "Comparison of Mobility-Limiting Mechanisms in High-Mobility Si _{1-x} Ge _x Heterostructures," Journal of Vacuum Science and Technology B, Vol. B11, Issue 4 (Jul/Aug 1993), pp. 1731-1737. C97 Nayak et al., "High-Mobility Strained-Sp. PMOSFET's," IEEE Transactions on Electron Devices, Vol. 43, No. 110 (October 1996), pp. 1709-1716. C98 Oh et al., "Interdigitated Ge p-i-n Photodetectors Fabricated on a Si Substrate Using Graded SiGe Buffer Layers," IEEE Journal of Opantum Electronics, Vol. 38, Issue 9 (Sept 2002), pp. 1238-1241. C99 Ohori et al., "Effect of Threading Dislocations on Mobility in Selectively Doped Heterostructures Grown on Si Substrates," Journal of Opantum Electronics, Vol. 75, Issue 7 (April 1, 1994), pp. 3681-3683. C100 O'Neill et al., "SiGe virtual substrate N-channel heterojunction MOSFETS," Semiconductor Science and Technology, Vol. 14 (1999), pp. 784-789. C101 Ota, "Application of heterojunction FET to power amplifier for cellular telephone," Electronic Letters, Vol. 30, No. 11(May 26, 1994), pp. 906-907. C102 Papananos, "Radio-Frequency Microelectronic Circuits for Telecommunication Applications," Kluwer Academic Publishers, 1999, pp. 115-117, 188-193. C103 Parker et al., "SiGe heterostructure CMOS circuits and applications," Solid State Electronics, Vol. 43 (1999), pp. 1497-1506. C104 Powell et al., "New Approach to the Growth of Low Dislocation Relaxed SiGe Material," Applied Physics Letters, Vol. 64, Issue 14 (April 4, 1994), pp. 1856-1858.														
INIT.														
1	Journal of Vacuum Science and Technology B, Vol. B11, Issue 4 (Jul/Aug 1993), pp. 1731-1737. C97 Nayak et al., "High-Mobility Strained-Si PMOSFET's," IEEE Transactions on Electron Devices, Vol. 43, No.													
		C98												
		C99												
		C10							nel he	terojunction	n MOSFET	'S," <u>Semiçor</u>	duc	tor Science and
		C10	:	30, No. 11(Ma	y 26, 19	94), p	p. 906 - 907.					•		
			1	Academic Pub	lishers,	1999, 1	pp. 115-117	7, 188	3-193.			•		·
		C10	3 1	Parker <i>et al.</i> , " pp. 1497-1506	SiGe her	erostr	ucture CM(OS ci	rcuits	and applica	tions," <u>Sol</u>	id State Elec	tron	ics, Vol. 43 (1999),
		C10									on Relaxed	SiGe Materi	ial,"	Applied Physics
		C10:										иOSFET's,"	<u>IEE</u>	EE Transactions on
		C10								channel M	OSFETs on	Si substrate	s,"]	Electronics Letters,
		C10											de-S	Semiconductor
d	1	C10		Rim <i>et al.</i> , "Er 520.	nhanced	Hole N	Mobilities in	n Sur	face-C	Channel Stra	ined-Si p-l	MOSFETs,"	IED	<u>OM</u> (1995), pp. 517-
EXA	MIN	ER (Ā	Muls	an			DAT	re co	ONSIDERI	ED (10/19	10	5

FORM I	PTO - 1	1449					AT	TORNEY	DOCKET	NO.: ASC	-066	5
INFORM	MATIC	N DISCLOS	URE S	TATI	EMENT		API	LICANT	(S): Westh	off et al.		
							SEF	JAL NO.:	10/765,37	72		
							 FIL	NG DAT	E: Januar	v 27. 2004	GR	2823 OUP: 2812 —
				11	S. PATE	NT						
EXAM.	T	DOCUMEN		DAT		_	ME	OWIDIVI	CLASS	SUB	FI	LING DATE IF
INIT.		NUMBER								CLASS	Al	PPROPRIATE
						<u> </u>						
				FOR	EIGN PA					r		T
EXAM INIT.	FOR XAM DOCUMENT DATE NIT. OTHER OTHER CXAM. OTHER DOCUMENTS: (Includent of the control of t				COUN- TRY CODE	CL	ASS	SUB CLASS	FILING DATE	ABSTRAC ONLY	T	ENGLISH LANG (Y/N)
EXAM. INIT.	ОТН	ER DOCUME	NTS: (I	includ	ing Author	, Tit	le, Da	te, Relevan	t Pages, Pi	ace of Publi	cati	on)
dm	C109								ined-Si N-N	MOSFET's,"	<u>IE</u>	EE Transactions on
	C110	Physics, Vol.	69, No.	6 (Mai	rch 15, 199	1), pp	372	9-3732.				
	C111	IEEE Transac	tions on	Electr	on Devices	(Aug	gust 19	96), pp. 12	24-1232.			
	C112	Symposium, \	√ol. 99-3	(1999	9), pp. 117-	121.				•		ternational SOI
	C113	Sakai <i>et al.</i> , " Strain – Relax 3400.	Reduction ation Pr	n of T ocedu	hreading D re," <u>Applied</u>	isloc i Phy	ation I sics L	Density in S etters, Vol.	iGe Layers 79, Issue 2	on Si (001) 1 (Novembe	Usii r 19	ng a Two-Step , 2001), pp. 3398-
	C114	Samavedam e (graded) / Si S	Structure	s," <u>Jo</u> u	rnal of App	olied	Physic	<u>s,</u> Vol. 87,	Issue 7 (A	oril 1, 1997),	pp.	3108-3116.
	C115	1515-1549.		-								, Vol. 12 (1997), pp.
	C116	3 (March 197	9), pp. 4	79-482	2.							ociety, Vol. 126, No.
	C117	Sugimoto et a Circuit," <u>IEIC</u>	E Trans	Electr	on, Vol.E8	2-C, 1	No. 7	(July 1999)	, pp. 1327-	1329.		
	C118	American Ins	titute of	Physic	s, Vol. 89,	Issue	8 (Ap	ril 15, 200	1), pp.4365	-4375.		nsity GaAs/Si,"
	C119	2000), pp. 38	-43.									," <u>IEEE</u> (October
	C120	Silicon Based	Optoele	ctroni	cs, Vol. 363	30 (Ja	ın 199	9), pp.19-2	8.			nference 1999-
4	C121	Tsang et al., " Physics, Vol.	Measure 75, No.	ments 12 (Ju	of alloy co ne 15, 1994	mpos), pp	ition : . 8098	and strain ir -8108.	n thin Ge _x S	_{1-x} layers," <u>J</u>	oun	nal of Applied
EXAMIN	ER (& WMel	sa_			DA	TE C	ONSIDER	ED	10/19	10	5

EXAM. DOCUMENT DATE FOREIGN F EXAM DOCUMENT DATE COUNTINIT. NUMBER TRY CODE OTHER ART, JO EXAM. OTHER DOCUMENTS: (Including Auth INIT.							AT	CORNEY	DOCKET	NO.: ASC	:-060	6	
INFOF	RMA	.TIO	N DISCLOS	URE S	TATI	EMENT		API	LICANT	(S): Westh	off et al.		
								SEF	UAL NO.:	: 10/765,37	<i>1</i> 2		
										·		GR	2823 ·
	—		· .				- 1/2	ļ		•	/ 21, 200		.OUI .~2012
			T - COUNTRY		, — ·		T		UMENI		· 	Г_	
	TORMATION DISCLOSURE STATEM U.S. MM. DOCUMENT NUMBER DOCUMENT NUMBER OTHER AI AM. OTHER DOCUMENTS: (Including Tr. C122 Tweet et al., "Factors determing Applied Physics Letters, Vol. of Buffer Structures," Journal of Buffer Structures," Journal of Buffer Structures," Journal of Buffer Structures," IEEE IDEM Technosphere al., "Relaxed, Low Thermal Chemical Vapor Dep 263-269. C124 Welser et al., "Electron Mobility Effect Transistors," IEEE IDEM Technosphere al., "Spectroscopic st Semiconductor Science and Telegraphy and the Structures," Journal of Buffer Structures," Journal of Buffer Structures," Journal of Buffer Structures, "IEEE IDEM Technosphere" [IEEE IDEM Technosphere] C125 Welser et al., "Svidence of Remosfets," IEEE IDEM Technosphere, "The Application of Signiconductor Field-Effect Transistors," IEEE IDEM Technosphere, "The Application of Signiconductor Field-Effect Transistors," IEEE IDEM Technosphere, "The Application of Signiconductor Field-Effect Transistors," IEEE IDEM Technosphere, "Silicon Processin CA, 1986, pp. 384-386. C131 Xie et al., "Fabrication of High Applied Physics, Vol. 73, Issue C132 Xie et al., "Semiconductor Sur Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C133 Xie et al., "Very High Mobility Physical Review Letters, Vol. C134 Xie et al., "Very High Mobility Physical Review Letters, Vol. C135 Xie et al., "Very High Mobility Physical Review Letters, Vol. C135 Xie et al., "Very High Mobility Physical Review Letters, Vol. C135 Xie et al., "Very High Mobility Physical			E	NA	ME .		CLASS	CLASS	1			
	TOTHER ARM. OTHER DOCUMENTS: (Including T. OTHER ARM. OTHER DOCUMENTS: (Including T. OTHER ARM. C122 Tweet et al., "Factors determining Applied Physics Letters, Vol. 6 and Valuena et al., "Influence of the Buffer Structures," Journal of C. C124 Valtuena et al., "Relaxed, Low T. C125 Watson et al., "Relaxed, Low T. Thermal Chemical Vapor Depo 263-269. C126 Welser et al., "Electron Mobility Effect Transistors," IEEE Electron Mobility Effect Transistors," IEEE IDEM Technology (C.) C128 Welser et al., "NMOS and PMC Structures," IEEE IDEM Technology (C.) C129 Welser, "The Application of Structures," IEEE IDEM Technology (C.) C129 Welser, "The Application of Structures," IEEE IDEM Technology (C.)												
					FOR'	EIGN PA	TE	NT D	OCUME	NTS			
U.S. PATENT DOCUMENTS EXAM. DOCUMENT DATE NAME CLASS SUB FILING APPRO FOREIGN PATENT DOCUMENTS EXAM DOCUMENT DATE COUNCLASS SUB FILING INIT. NUMBER DATE COUNCLASS SUB FILING TRY CODE CLASS DATE ONLY (Y/N CODE CLASS DATE CLASS DATE ONLY (Y/N CODE CLASS DATE CLASS DATE ONLY (Y/N CODE CLASS DATE CLASS DATE CLASS DATE CLASS DATE CLASS DATE CLASS C								ENGLISH LANG					
INIT.		N	/UMBER		!				CLASS	DATE	ONLY		(Y/N)
<u> </u>		十			SERIAL NO.: 10/765,372 FILING DATE: January 27, 2004 GROUP:—28+2- U.S. PATENT DOCUMENTS DATE NAME CLASS CLASS SUB FILING DATE IF APPROPRIATE FOREIGN PATENT DOCUMENTS TE COUN- TRY CODE CLASS SUB FILING ABSTRACT ONLY COLESS CLASS CLASS FILING ABSTRACT ONLY CYN) COTHER ART, JOURNAL ARTICLES, ETC. S: (Including Author, Title, Date, Relevant Pages, Place of Publication) TOTHER ART, JOURNAL ARTICLES, ETC. S: (Including Author, Title, Date, Relevant Pages, Place of Publication) TOTHER ART, JOURNAL ARTICLES, ETC. S: (Including Author, Title, Date, Relevant Pages, Place of Publication) Total determining the composition of strained GeSi layers grown with disilane and germane," **etters**, Vol. 65, No. 20 (November 14, 1994), pp. 2579-2581. Ctroscopic study of Si-based quantum wells with neighboring confinement structure," **ience and Technology**, (1997), abstract. Thuence of the Surface Morphology on the Relaxation of Low-Strained In _x Ga _{1-x} As Linear "Journal of Crystal Growth, Vol. 182 (1997), pp. 281-291. Claxed, Low Threading Defect Density Si _{0-x} Ge ₀₋₃ Epitaxial Layers Grown on Si by Rapid I Vapor Deposition," Journal of Applied Physics, Vol. 75, Issue 1 (January 1, 1994), pp. **Certon Mobility Enhancement in Strained-Si N-Type Metal-Oxide-Semiconductor Field- "IEEE Electron Device Letters, Vol. 15, No. 3 (March 1994), pp. 100-102. **Idence of Real-Space Hot-Electron Transfer in High Mobility, Strained-Si Multilayer **IDEM Technical Digest (1993 International Electron Devices Meeting), pp. 545-548. **IGOS and PMOS Transistors Fabricated in Strained Silicon/Relaxed Silicon-Germanium Heterostructures to Metal-Oxide- **Idence of Strained Silicon/Relaxed Silicon Germanium Heterostructures to Metal-Oxide- **Idence of Strained Silicon/Relaxed Silicon Germanium Heterostructures to Metal-Oxide- **Idence of Strained Silicon/Relaxed Silicon Germanium Heterostructures to Metal-Oxide- **Idence of Technical Digest (1992 International Electron Devices Meeting), pp. 1-205. **Idence of								
				OTF	IER .	ART, JOI	URN	JAL 1	ARTICLE	ES, ETC.	Ł		
	C)THF	ER DOCUME								ace of Publi	cati	on)
INIT. C122 Tweet et al., "Factors determining the composition of strained GeSi layers grown with disilane and germane Applied Physics Letters, Vol. 65, No. 20 (November 14, 1994), pp. 2579-2581.									ilane and germane,"				
1	Applied Physics Letters, Vol. 65, No. 20 (November 14, 1994), pp. 2579-2581. C123 Usami et al., "Spectroscopic study of Si-based quantum wells with neighboring confinement structure,"											ent structure,"	
	C	124										ined	In _x Ga _{1-x} As Linear
	C	125	Thermal Chen										
	C	126	Welser et al., Effect Transis	"Electron stors," <u>IE</u>	n Mob EE El	ility Enhan	ceme	ent in S	Strained-Si ? Vol. 15, No	N-Type Me o. 3 (March	tal-Oxide-Se 1994), pp. 1	emic 100-	conductor Field- 102.
			MOSFETs," <u>I</u>	IEEE IDE	EM Te	chnical Dig	gest (1	1993 I	International	d Electron I	Devices Mee	ting	g), pp. 545-548.
	С		Structures," IE	EEE IDE	M Tec	chnical Digo	<u>est</u> (1	1992 In	nternational	l Electron D	Devices Meet	ting)), pp. 1000-1002.
			Semiconducto	or Field-E	Effect 1	Transistors,	," PhI	D Thes	sis, Stanford	d University	y, 1994, pp.	1-20	05.
	C					sing for the	VLS	I Era,	Vol. 1: Pro	cess Techno	ology," Latti	ce P	ress, Sunset Beach,
	C										Hole Gases	in G	eSi/Si," <u>Journal of</u>
	C											of Bu	ulk Strain," <u>The</u>
	C												
1	c		Xie, "SiGe Fie										
EXAMI	NER	.0	Moles	an			DA	TE C	ONSIDERI	ED	10/191	10	5

FORM I	·OT	1449					ΑT	TORNEY	DOCKET	NO.: ASC	-066	5
INFORM	/ATI	ON DISCLOS	URE S	TATE	EMENT		API	PLICANT	(S): Westh	off et al.		
:							SEF	UAL NO.:	10/765,37	72		2620
							FIL	ING DAT	E: Januar	y 27, 2004	GR	
				U	.S. PATE	NT	DOC	UMENT	S			
INFORMATION DISCLOSURE STATEMENT ATTORNEY DOCKET NO.: ASC-066 APPLICANT(S): Westhoff et al. SERIAL NO.: 10/765,372 FILING DATE: January 27, 2004 GROUP: -2812- U.S. PATENT DOCUMENTS EXAM. DOCUMENT NUMBER DATE FOREIGN PATENT DOCUMENTS EXAM INIT. DOCUMENT DATE FOREIGN PATENT DOCUMENTS EXAM INIT. DOCUMENT DATE CLASS SUB FILING DATE IF APPROPRIATE CLASS DATE ONLY ONLY ONLY OTHER ART, JOURNAL ARTICLES, ETC. EXAM. OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication) INIT. C135 Yamagata et al., "Bonding, Splitting and Thinning by Porous Si in ELTRAN®; SOI-Epi Wafer™," Materia Research Society Symposium Proceedings, Vol. 681E (2001); pp. 18.2.1-18.2.10. C136 Yeo et al., "Nanoscale Ultra-Thin-Body Silicon-on-Insulator P-MOSFET with a SiGe/Si Heterostructure Channel," IEEE Electron Device Letters, Vol. 21, No. 4 (April 2000), pp. 161-163. C137 Zhang et al., "Demonstration of a GaAs-Based Compliant Substrate Using Wafer Bonding and Substrate Removal Techniques," Electronic Materials and Processing Research Laboratory, Department of Electrical Engineering, University Park, PA 16802, 1998, pp. 25-28. C138 "Optimal Growth Technique and Structure for Strain Relaxation of Si-Ge Layers on Si Substrates," IBM Technical Disclosure Bulletin, Vol. 32, No. 8A (January 1990), pp. 330-331.												
		<u>.</u>		FOR	EIGN PA	TEN	T D	OCUME	NTS			
	AM DOCUMENT DATE NUMBER				TRY	CL	ASS				r	ENGLISH LANG (Y/N)
			OTH	ER A	ART, JOI	JRN	AL A	ARTICLE	ES, ETC.			
	ОТН	IER DOCUME	NTS: (I	nclud	ing Author	, Titl	e, Da	te, Relevan	t Pages, Pl	ace of Public	catio	on)
Alm	C135										Epi V	Vafer™," <u>Materials</u>
	C136										/Si F	leterostructure
	C137	Removal Tecl	nniques,"	Elect	ronic Mater	rials a	ınd Pr	ocessing Re				
	C138										i Sut	ostrates," <u>IBM</u>
V	C139	"2 Bit/Cell El Bulletin, Vol.							Data Read-	Out," <u>IBM</u> 1	(ech	nical Disclosure
EXAMIN	ER (Alma	ln_			DA	TE C	ONSIDER	ED	10/10	7/	05

FORM	110 -	1449				ATTORN	EY DOCK	ET NO.: A	ASC-066		
SUPPL	EMEN	TAL INFORM	MATION	1		APPLICA	NTS: W	esthoff et a	ıl.		
DISCL	S URI	estatemen	NT			SERIAL N	IO.: 10/76	5,372			
	LPR 18	્છું. 2005 હ				FILING D	ATE: Janı	uarv 27. 20	04		
E	UN 1 5										
	E THAT!	Me City				GROUP:		75			
				U.S	_	NT DOCUI	MENTS	1	1	T	·
EXAM. INIT.		DOCUMENT NUMBER			DATE	NAME		CLASS	SUB CLASS		ING DATE
	A198	US 2002/18568	6-A1	12	/12/2002	Mooney et a	l				
	A199	US 4 914 488 7		04.	/03/1990	Mishima et			1		
	A200	US 4 960 728 /		10.	/02/1990	Schaake et a	1.		/		
	A201	US 6 208 005 F	31	03	/27/2001	Mitra					
	A202	US 6-515-335 E		02	/04/2003	- Christianser	Let al.	1		╁	
										F	
				 					<u> </u> .		
										-	
*			FO	DE	ICNI DAT	ENT DOC	יו וארבאויו	YC .			
EXAM.		DOCUMENT	DATE	/KE	COUNTR		SUB	FILING	ABSTRA	СТ	ENGLISH
INIT.		NUMBER	DALL		CODE	CLASS	CLASS	DATE	ONLY		LANG (Y/
,-											
											
		-									
	1		OTHE	R A	RT, IOU	RNAL AR	TICLES.	ETC.			
EXAM.	ОТН	ER DOCUME				<u>·</u>			ace of Pub	licat	ion)
INIT.											
AM	C140	International S	earch Rep	ort f	or PCT/US2	2004/002282,	October 4, 2	2004, 6 pag	es.		
										,	
		1									

*-Already listed on the IDS (1449) filed on Nov. 5, 2004

LIBC/2441869.1